

L Number	Hits	Search Text	DB	Time stamp
3	13	("4655594" "5040431" "5528118" "5610686" "5623853" "5699621" "5760564" "5858587" "5864389" "5909272" "5939852" "6028376" "6038013").PN.	USPAT	2003/04/11 11:55
4	9	("4698575" "4869481" "5040431" "5184055" "5280677" "5376988" "5382095" "5440397" "5671058").PN.	USPAT	2003/04/11 12:02
5	7359	355/53-74.cc1s.	USPAT; US-PGPUB	2003/04/11 12:09
6	17	355/53-74.cc1s. and (hold\$3 adj3 rotate)	USPAT; US-PGPUB	2003/04/11 12:12
7	1819	355/53-74.cc1s. and wafer	USPAT; US-PGPUB	2003/04/11 12:12
8	24	355/53-74.cc1s. and (rotate adj3 wafer)	USPAT; US-PGPUB	2003/04/11 12:12
9	24	(355/53-74.cc1s. and (rotate adj3 wafer)) not (355/53-74.cc1s. and (hold\$3 adj3 rotate))	USPAT; US-PGPUB	2003/04/11 12:28
10	19	("3541338" "4758863" "4841341" "4905041" "5160957" "5476736" "5498501" "5539497" "5673103" "5726741" "5849437" "5854671" "5883700" "5933219" "5995200" "6020092" "6074787" "6078381" "6090527").PN.	USPAT	2003/04/11 12:14
11	486	wafer and (rotat\$3 adj3 ("180" adj2 degrees))	USPAT; US-PGPUB	2003/04/11 12:30
12	0	(wafer and (rotat\$3 adj3 ("180" adj2 degrees))) and (rotat\$3 adj3 ("25" adj2 degrees))	USPAT; US-PGPUB	2003/04/11 12:30
13	245	(wafer and (rotat\$3 adj3 ("180" adj2 degrees))) and motor	USPAT; US-PGPUB	2003/04/11 12:31
14	166	((wafer and (rotat\$3 adj3 ("180" adj2 degrees))) and motor) and stage	USPAT; US-PGPUB	2003/04/11 12:31
15	5	((((wafer and (rotat\$3 adj3 ("180" adj2 degrees))) and motor) and stage) and damper	USPAT; US-PGPUB	2003/04/11 12:33
16	84	((((wafer and (rotat\$3 adj3 ("180" adj2 degrees))) and motor) and stage) and vibration	USPAT; US-PGPUB	2003/04/11 12:33
17	82	((((wafer and (rotat\$3 adj3 ("180" adj2 degrees))) and motor) and stage) and vibration) not (((((wafer and (rotat\$3 adj3 ("180" adj2 degrees))) and motor) and stage) and damper)	USPAT; US-PGPUB	2003/04/11 12:36
18	84	((((wafer and (rotat\$3 adj3 ("180" adj2 degrees))) and motor) and stage) not (((((wafer and (rotat\$3 adj3 ("180" adj2 degrees))) and motor) and stage) and vibration) not (((((wafer and (rotat\$3 adj3 ("180" adj2 degrees))) and motor) and stage) and damper))	USPAT; US-PGPUB	2003/04/11 12:40
19	46983	318/\$.cc1s.	USPAT; US-PGPUB	2003/04/11 12:41
20	321	318/\$.cc1s. and wafer	USPAT; US-PGPUB	2003/04/11 12:41
21	38	318/\$.cc1s. and (rotat\$3 adj2 wafer)	USPAT; US-PGPUB	2003/04/11 12:43
22	14068	(exposure adj2 (apparatus device))	USPAT; US-PGPUB	2003/04/11 12:44
23	368	((exposure adj2 (apparatus device))) and (wafer adj3 rotat\$3)	USPAT; US-PGPUB	2003/04/11 12:45
24	44	((((exposure adj2 (apparatus device))) and (wafer adj3 rotat\$3)) and gravity	USPAT; US-PGPUB	2003/04/11 12:45
25	31	((((exposure adj2 (apparatus device))) and (wafer adj3 rotat\$3)) and (stage adj3 motor))	USPAT; US-PGPUB	2003/04/11 12:45

26	115	((exposure adj2 (apparatus device))) and (wafer adj3 rotat\$3) and (damp\$3 vibration)	USPAT; US-PGPUB	2003/04/11 12:46
27	140	((exposure adj2 (apparatus device))) and (wafer adj3 rotat\$3) and gravity (((exposure adj2 (apparatus device))) and (wafer adj3 rotat\$3) and (stage adj3 motor)) (((exposure adj2 (apparatus device))) and (wafer adj3 rotat\$3) and (damp\$3 vibration))	USPAT; US-PGPUB	2003/04/11 12:58
28	7	(("6486941") or ("4698575") or ("6522389") or ("4910549") or ("5641264") or ("4887904") or ("4775877")).PN.	USPAT; US-PGPUB	2003/04/11 12:58
-	365	(wafer adj3 holder) same rotate	USPAT; US-PGPUB	2003/04/09 14:47
-	105	((wafer adj3 holder) same rotate) and exposure	USPAT; US-PGPUB	2003/04/09 14:47
-	62	((wafer adj3 holder) same rotate) and exposure) and motor	USPAT; US-PGPUB	2003/04/09 14:50
-	62284	(semiconductor wafer) same (rotat\$4 turn\$4)	USPAT; US-PGPUB	2003/04/09 14:52
-	27925	((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)	USPAT; US-PGPUB	2003/04/09 14:58
-	2070	((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device))	USPAT; US-PGPUB	2003/04/09 14:59
-	992	((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor	USPAT; US-PGPUB	2003/04/09 14:59
-	0	((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor) and ("25" adj2 degrees)	USPAT; US-PGPUB	2003/04/09 15:00
-	59	((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor) and (wafer adj2 stop\$3)	USPAT; US-PGPUB	2003/04/09 15:00
-	352	((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor) and (355/.cc1s.)	USPAT; US-PGPUB	2003/04/09 15:00
-	40	((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor) and (318/.cc1s.)	USPAT; US-PGPUB	2003/04/09 15:01
-	415	((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor) and (wafer adj2 stop\$3)) ((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor) and (355/.cc1s.) ((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor) and (318/.cc1s.)	USPAT; US-PGPUB	2003/04/09 15:01
-	63	((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor) and (wafer adj2 stop\$3)) ((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor) and (355/.cc1s.) ((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device)) and motor) and (318/.cc1s.)) and (damp\$4)	USPAT; US-PGPUB	2003/04/09 15:09

-	9	("4989031" "5473410" "5528118" "5559584" "5909272" "5982128" "6087797" "6252314" "6271606").PN.	USPAT	2003/04/09 15:03
-	12	("3940676" "5153494" "5204712" "5260580" "5467720" "5518550" "5528118" "5610686" "5684856" "5773951" "5841250" "5909272").PN.	USPAT	2003/04/09 15:05
-	15	((((((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device))) and motor) and (wafer adj2 stop\$3)) (((((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device))) and motor) and (355/\$.ccls.)) (((((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device))) and motor) and (318/\$.ccls.)) and (damp\$4)) and (((((semiconductor wafer) same (rotat\$4 turn\$4)) and (stage table)) and (exposure adj2 (apparatus system device))) and motor) and (wafer adj2 stop\$3))	USPAT; US-PPGPUB	2003/04/09 15:13
-	46978	318/\$.ccls.	USPAT; US-PPGPUB	2003/04/09 15:13
-	321	318/\$.ccls. and wafer	USPAT; US-PPGPUB	2003/04/09 15:13
-	58	(318/\$.ccls. and wafer) and damp\$3	USPAT; US-PPGPUB	2003/04/09 15:14
-	107	318/\$.ccls. and (moving adj2 stage)	USPAT; US-PPGPUB	2003/04/09 15:15
-	98	(318/\$.ccls. and (moving adj2 stage)) and motor	USPAT; US-PPGPUB	2003/04/09 15:15
-	25	((318/\$.ccls. and (moving adj2 stage)) and motor) and damp\$3	USPAT; US-PPGPUB	2003/04/09 15:19
-	41	(318/\$.ccls. and wafer) and (rotat\$3 adj3 (wafer (semiconductor adj2 device)))	USPAT; US-PPGPUB	2003/04/09 15:26
-	41	((318/\$.ccls. and wafer) and (rotat\$3 adj3 (wafer (semiconductor adj2 device)))) not ((318/\$.ccls. and (moving adj2 stage)) and motor) and damp\$3)	USPAT; US-PPGPUB	2003/04/09 15:32
-	7	((("5959427") or ("6304320") or ("6373153") or ("6486941") or ("6437463") or ("6316901") or ("6355994"))).PN.	USPAT; US-PPGPUB	2003/04/11 12:09